

Optical Properties of Textured V₂O₅/Si Thin Films Deposited by Reactive Magnetron Sputtering

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Abstract – Thin films of V₂O₅ are formed on Si substrates by reactive DC magnetron sputtering of vanadium metal target in Ar/O₂ low pressure gas mixture. The phase composition of the films was examined with reflection high energy electron diffraction (RHEED) at 65 keV and the presence of V₂O₅ textured polycrystal with preferential orientation of [100] was found for the range of 35.4–48.9% O₂ partial pressure. Optical characterization of the films was produced with spectroscopic ellipsometry (SE) over the spectral range 250–800 nm.

1. Introduction

Vanadium pentoxide, V₂O₅, is the most stable oxide in V–O system exhibiting a semiconductor-metal transition at ~250°C. V₂O₅ thin films exhibit multicoloured electrochromism, and have high potential for use in electrochromic display devices, colour filters, and other optical devices [1–5]. V₂O₅ thin films can also be used in variable reflectance mirrors, smart windows, and surfaces with tunable emittance for temperature control of space vehicles. Layered crystal structure of V₂O₅ opens a possibility for gentle tuning of their physical characteristics via chemical intercalation of different metals yielding excellent film material for rechargeable microbatteries.

Heat treatment of V₂O₅ films results in nanostructuring of material which final chemical composition and geometry are dependent on temperature and atmosphere composition. These vanadium oxide nanophases have enhanced ability for metal intercalation and gas sensitivity and are promising for effective applications in electronic devices.

2. Experimental

Thin films of V₂O₅ were deposited on Si(100) substrates by reactive DC magnetron sputtering of vanadium metal target in (O₂ + Ar) low pressure gas mixture. The phase composition of the films was examined with reflection high energy electron diffraction (RHEED). The presence of V₂O₅ textured polycrystal with preferential orientation of [100] was found for the range of 32.7–40.8% O₂/(O₂ + Ar) pres-

sure ratio. Typical RHEED pattern of textured film is shown in Fig. 1.

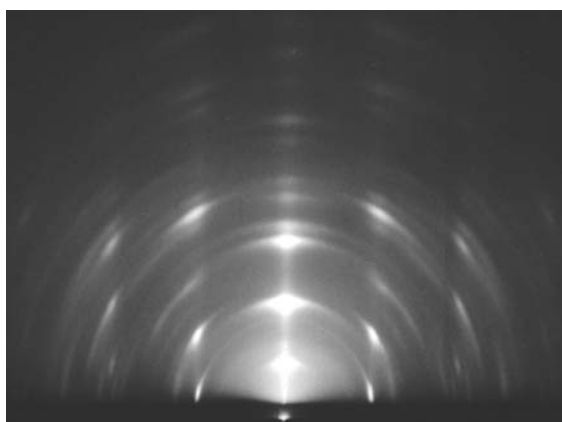


Fig. 1. RHEED pattern observed for V₂O₅ film formed at O₂/Ar ratio 32.7%

The films are polycrystal without pronounced ordering for the range of 40.8–48.9% O₂ partial pressure. Presence of unique V⁵⁺ valence state for vanadium ions in the film has been confirmed with X-ray photoelectron spectroscopy (XPS). Spectral dependences of refractive index n and extinction coefficient k and film thickness d were determined with using spectral ellipsometer “Spectroscan”. Ellipsometric parameters were measured over wavelength range 250–900 nm at incident angle 70° with spectral resolution 2 nm. The V₂O₅ films are transparent in the spectral range 500–900 nm and refractive index dispersion was approximated by Cauchy polynomials:

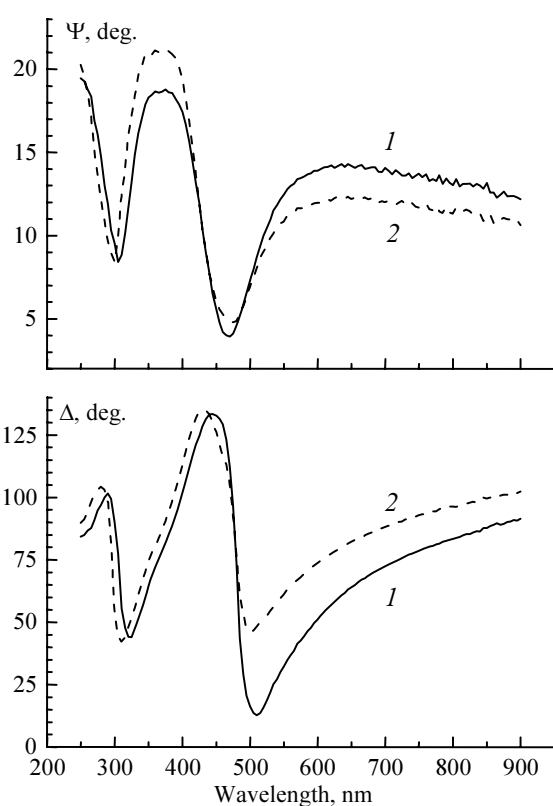
$$n(\lambda) = a + \frac{b}{\lambda^2} + \frac{c}{\lambda^4}. \quad (1)$$

In the short wavelength spectral range $\lambda < 500$ nm a strong absorption has been detected. Well fitting of experimental curves can be achieved by introduction of two oscillators. Then Lorentz–Drude dispersion model (2) was applied with parameters shown in Table 1:

$$\varepsilon(E) = \varepsilon_{\infty} - \frac{E_{1D}^2}{E^2 - i E_{2D} E} + \sum_{n=1}^m \frac{A_n E_n^2}{E_n^2 - E^2 + i \Gamma_n E_n E}. \quad (2)$$

Table I. Dispersion parameters for $V_2O_5/Si(100)$ systems

$\lambda = 500\text{--}900$ nm, Cauchy polynomials					
Sample	Thickness, nm	a	$b \cdot 10^{-4}$	$c \cdot 10^{-10}$	σ
1	43.29	2.45	-6.55	5.54	11.3
2	36.17	2.51	-6.38	5.48	17.5
$\lambda < 500$ nm, Lorentz-Drude dispersion model					
Sample	ϵ_∞	A_n	E_n , eV	Γ_n	σ
1	3.38	1.62	3.07	0.19	39.7
		2.15	4.71	0.35	
2	3.44	1.75	3.12	0.16	53.8
		2.29	4.80	0.31	

Fig. 2. Dependencies $\Psi(\lambda)$ and $\Delta(\lambda)$ for system $V_2O_5/Si(100)$. Samples are shown by numbers

In the spectral range $\lambda = 250\text{--}500$ nm the strong maximums of absorption in $V_2O_5/Si(100)$ films are positioned at photon energy $E_2 \sim 3.1$ and $E_4 \sim 4.7$ eV. These results are well consistent with optical properties of V_2O_5 single crystal determined earlier with spectroscopic methods over a range $E = 2\text{--}14$ eV. In all these studies the most intensive absorption peak was observed at $E \sim 2.9\text{--}3.0$ eV that is well relates with $E_2 \sim 3.1$ eV determined in our experiments for $V_2O_5/Si(100)$ films. This dominant spectral feature relates to optical transitions from the top part of valence band to the pair of localized conductivity bands. The absorption peak at $E_4 \sim 4.7$ eV is related to the transitions from the top of valence band to upper conductivity band.

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